



PTO/SB/08B (08-03)

INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)		Compleat If Known			
		Application Number	10/680,874		
		Filing Date	October 6, 2003		
		First Named Inventor	Farrens, Sharon N.		
		Art Unit	To Be Assigned 2829		
		Examiner Name	To Be Assigned Per		
Sheet	2	of	2	Attorney Docket Number	18419D-009011US

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials *	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
EF	0011	Kissinger, G., and Kissinger, W. (1993) "Void-free silicon-wafer-bond strengthening in the 200-400 C range," Sensors and Actuators, Vol. A36, No. 2, pp. 149-156.	
EF	0012	Roberts, B.E. (1998). "Science and Technology of Plasma Activated Direct Wafer Bonding," PhD Dissertation, University of California at Davis, School of Engineering, pp. 1-120.	
EF	0013	Watt, V.H.C. and Bower, R.W., (1994). "Low Temperature Bonding Direct of Non-Hydrophilic Surfaces," Electronics Letters, pp. 693-695.	

Examiner Signature	<i>Even Per</i>	Date Considered	8-6-04
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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹ Applicant's unique citation designation number (optional). ² Applicant is to place a check mark here if English language Translation is attached.